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NORTH AMERICA INTERNATIONAL PATENT OFFICE (NAIPC)  
P.O. BOX 506  
MERRIFIELD VA 22116

In re Application of:  
Yung-Huei Chen et al.  
Serial No.: 10/065,967  
Filed: December 5, 2002  
For: STATE MACHINE, COUNTER AND  
RELATED METHOD FOR GATING  
REDUNDANT TRIGGERING CLOCKS  
ACCORDING TO INITIAL STATE

DECISION ON PETITION TO  
WITHDRAW HOLDING  
OF ABANDONMENT

This is a decision on the petition filed November 9, 2004, via facsimile transmission, to withdraw the holding of abandonment of the above-identified application.

The petition is GRANTED.

A non-final Office action was mailed March 4, 2004, setting a three-month shortened statutory period for filing a reply. In the apparent absence of a response, a Notice of Abandonment was mailed on October 15, 2004.

Petitioner asserts that a reply was timely filed. In support of the assertion that a reply was timely filed, petitioner submitted the following papers as evidence of timely submission: 1) a copy of a response, 2) a Certificate of Transmission under 37 C.F.R. § 1.8(a) dated May 26, 2004, and 3) a copy of an Auto-Reply Facsimile Transmission acknowledging receipt of the 17-page transmission on May 26, 2004. To further support the assertion, it is stated that the record in the PAIR system indicates an entry of "Workflow incoming amendment IFW" dated May 26, 2004.

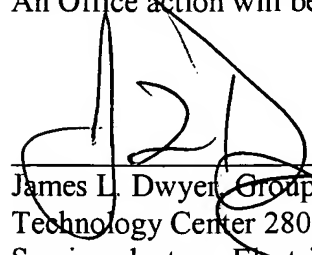
The file record includes the originally submitted reply of May 26, 2004.

The Notice of Abandonment is hereby vacated and the holding of abandonment withdrawn. Inconvenience to the applicant is regretted.

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Any inquiry regarding this decision should be directed to Hien H. Phan, Special Program Examiner, at (571) 272-1606.

An Office action will be issued in due course.



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James L. Dwyer, Group Director  
Technology Center 2800  
Semiconductors, Electrical and Optical  
Systems and Components